



Silicon Sensor with Readout ASICs for EXAFS Spectroscopy

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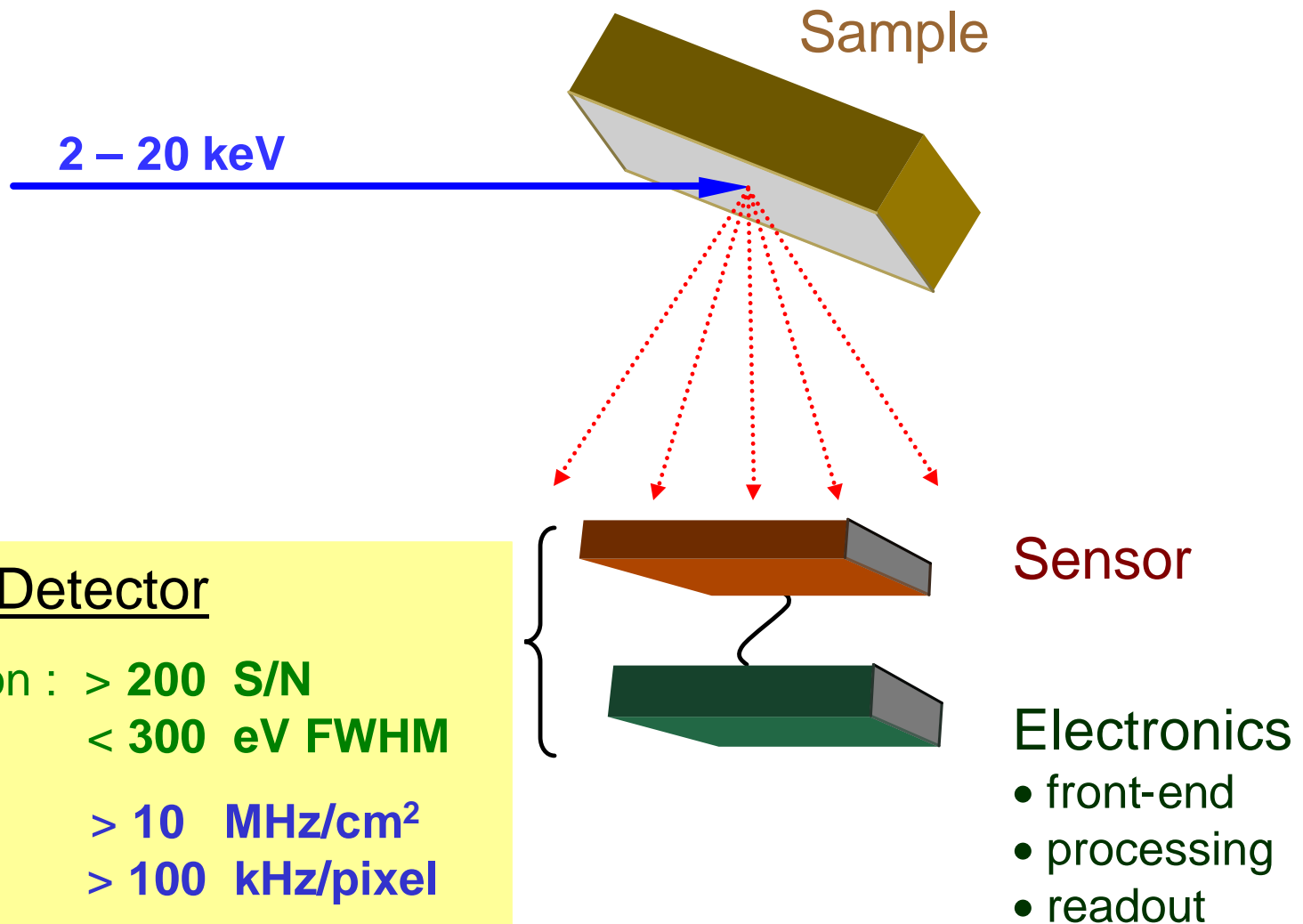
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Typical fluorescence EXAFS spectroscopy geometry



Detector

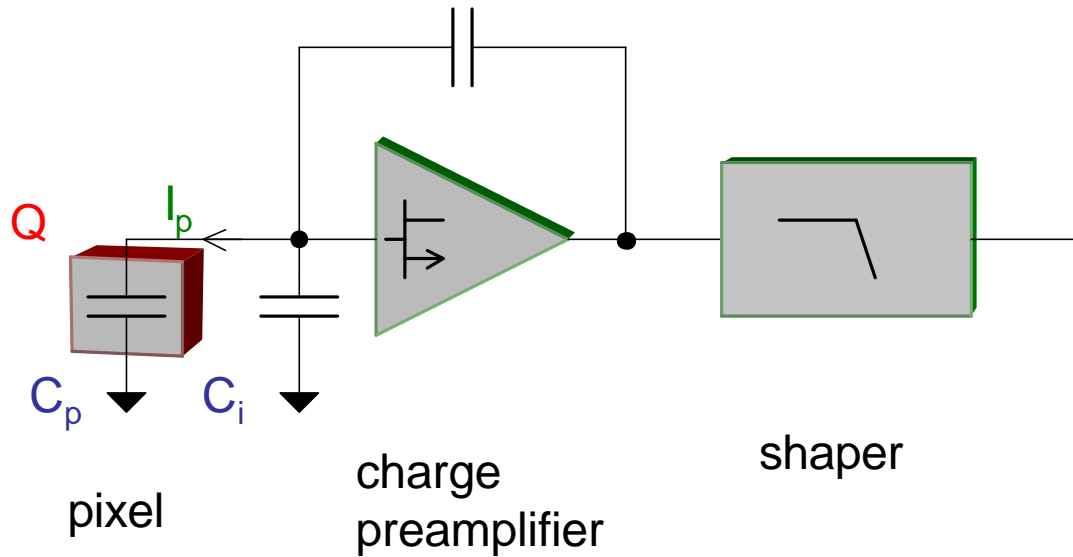
- Resolution : > 200 S/N
< 300 eV FWHM
- Rate : > 10 MHz/cm²
> 100 kHz/pixel
- Spectroscopy (energy windows)

Sensor

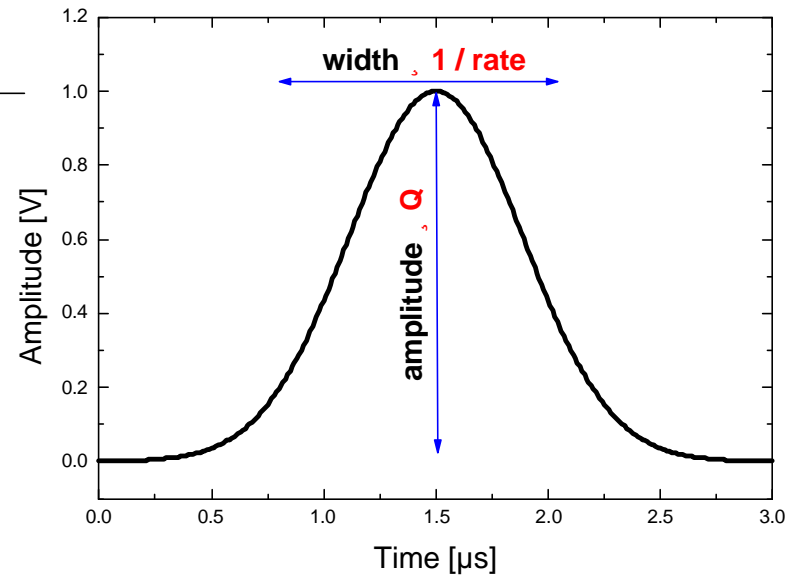
Electronics

- front-end
- processing
- readout

Resolution vs Rate

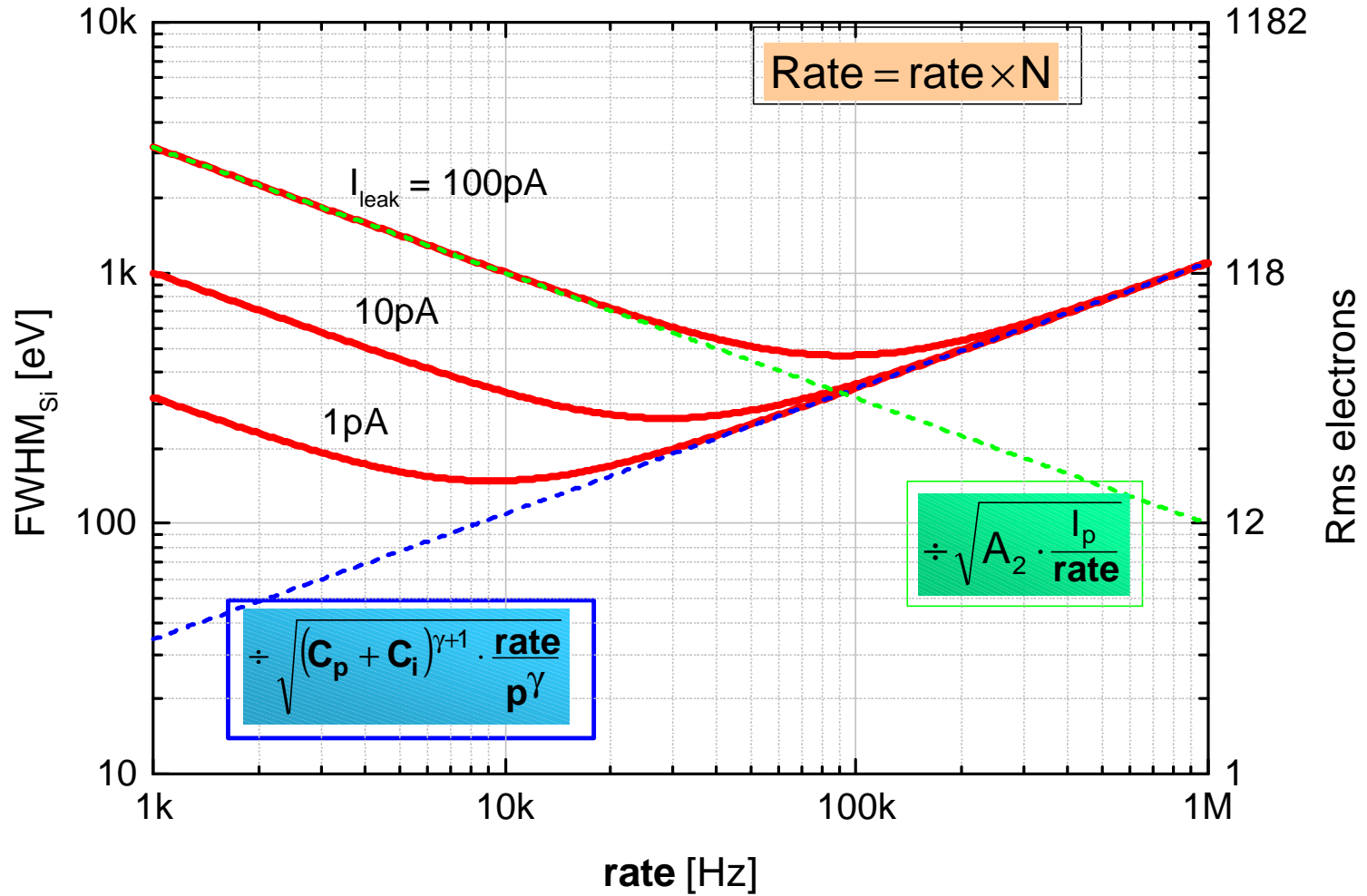


$$\text{rate} = \frac{\text{Rate}}{N} \quad (N = \text{number of pixels})$$

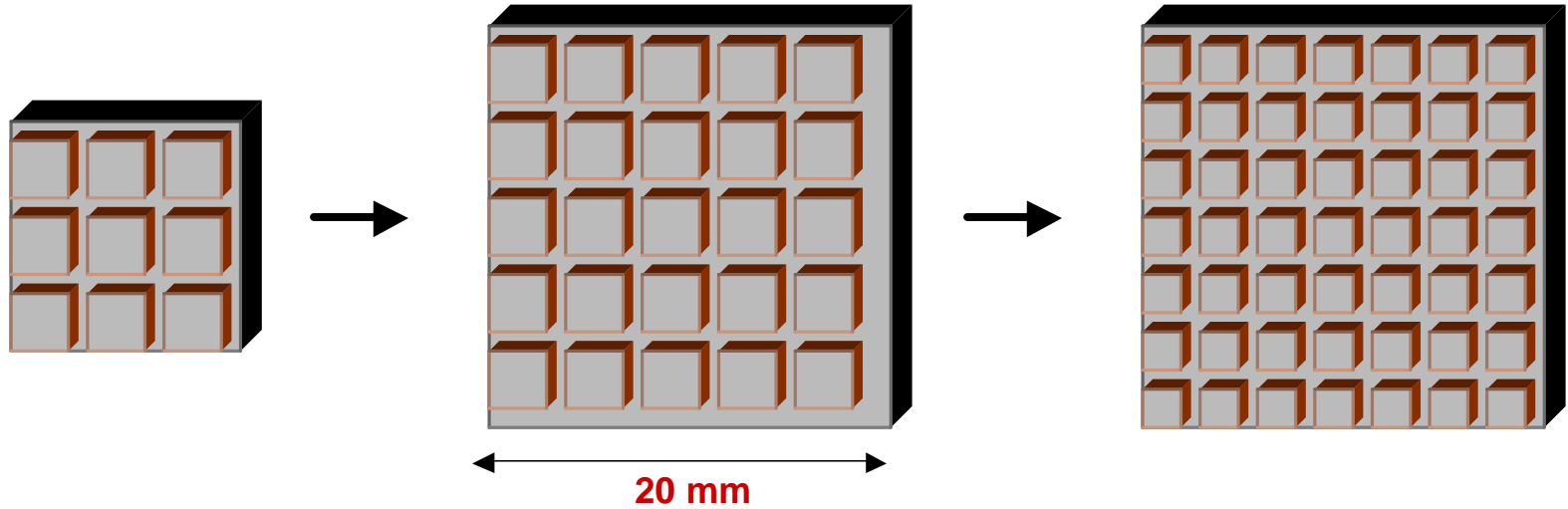


$$\text{ENC}^2 = A_1(\gamma)(C_p + C_i)^{\gamma+1} \frac{\text{rate}}{p^\gamma} + A_2 \frac{I_p}{\text{rate}} \quad 0 < \gamma < 1$$

Resolution vs Rate



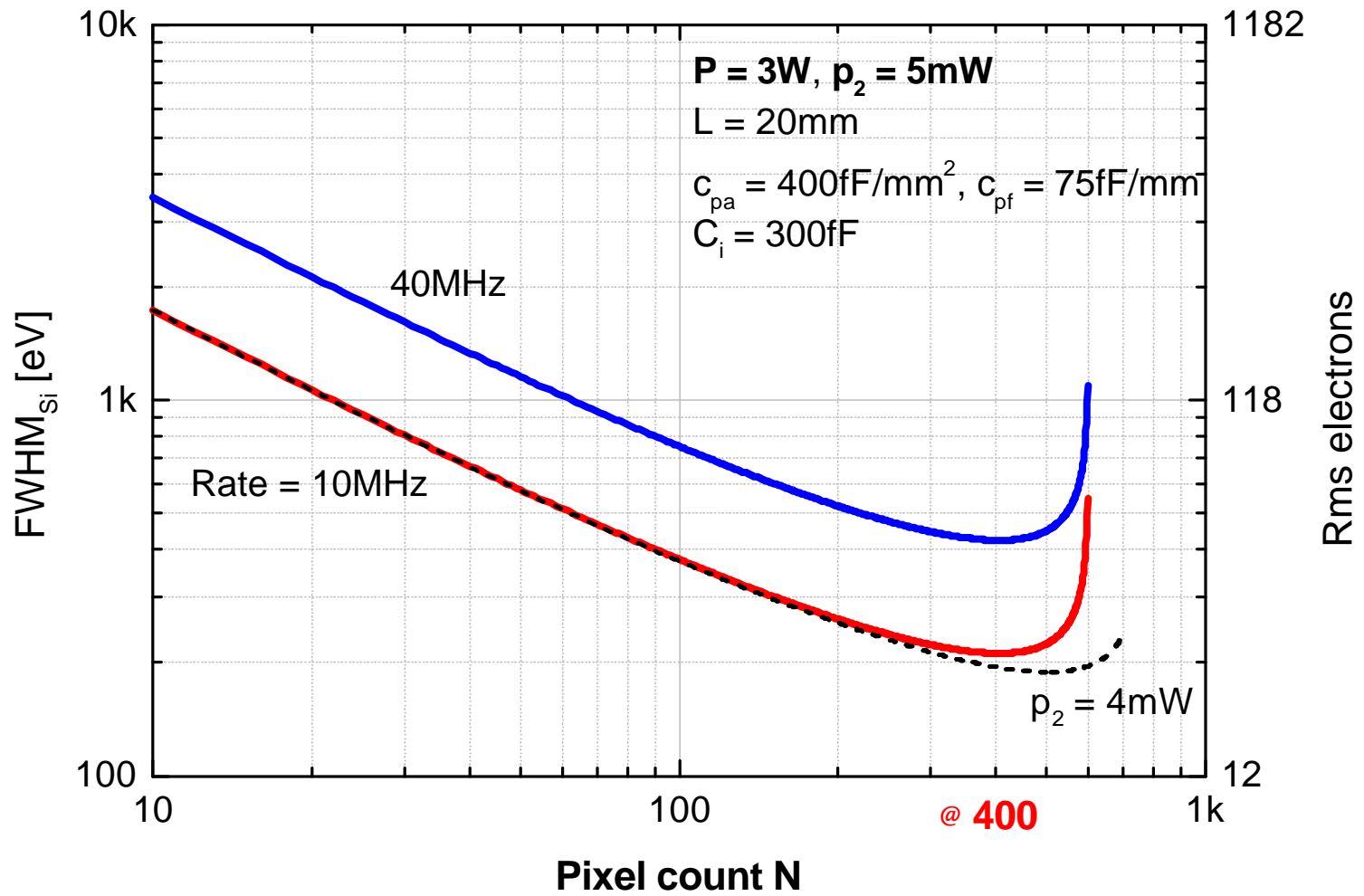
Optimum pixellation

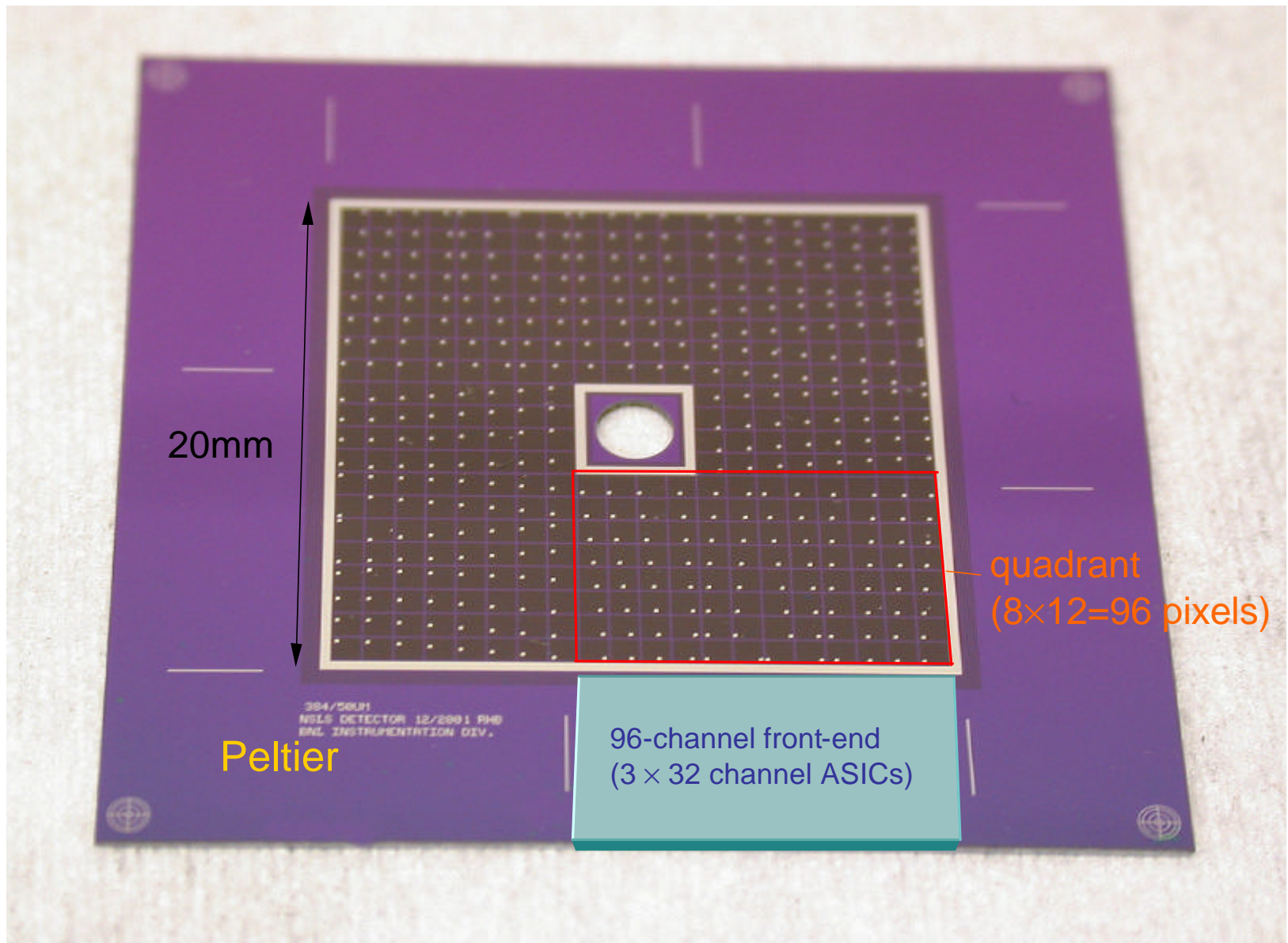


$$\text{ENC}^2 \div (C_p(N) + C_i)^{\gamma+1} \frac{\frac{\text{Rate}}{N}}{\left(\frac{P}{N} - p_2\right)^\gamma}$$

- charge sharing ($\approx 20\mu\text{m}/\text{side}$) and trapping (gap/side) : empirical

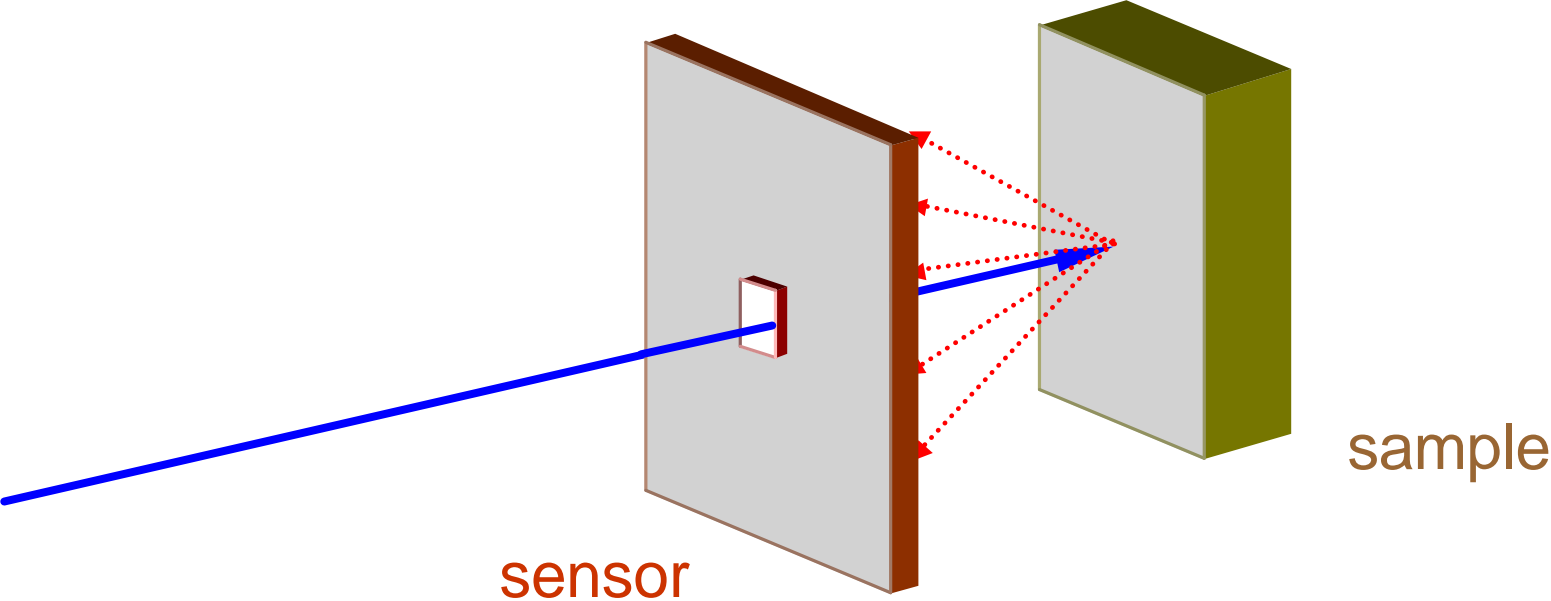
Optimum pixellation



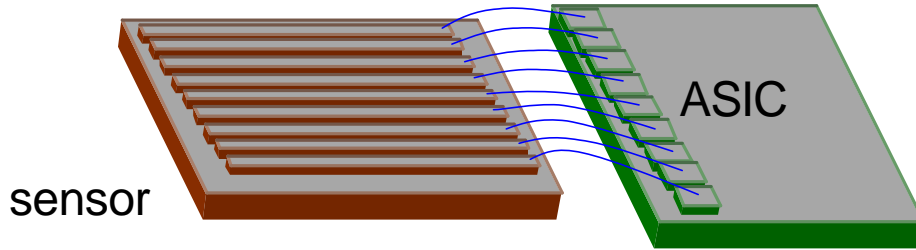


Si n-type high resistivity wafer 250 μ m thick,
 $N = 384$ $p^+ \approx 1\text{mm} \times 1\text{mm}$ pixels, $C_p \approx 700\text{-}1000\text{fF}$
gaps 10 μ m, 30 μ m, 50 μ m

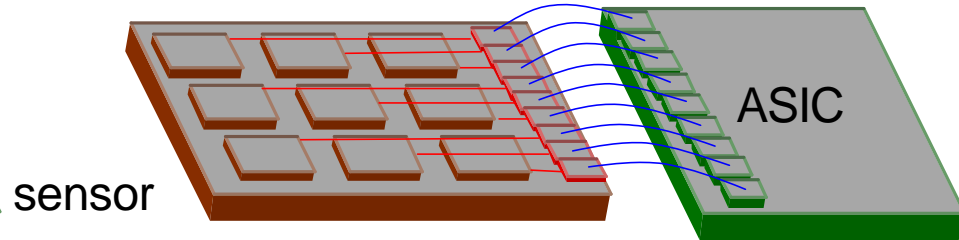
Beam through



Interconnecting pixel to front-end electronics

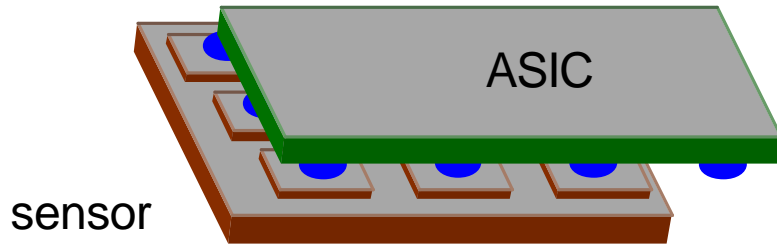


- + interconnect parasitic
- + bond length
- fringe capacitance
- charge sharing and trapping

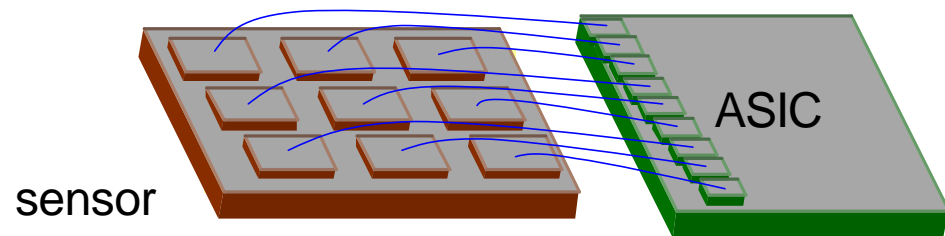


- + bond length
- interconnect parasitic
- dielectric losses

$6\text{mm} \times 10\mu\text{m}$, Si_3N_4 ($\epsilon_r=6.5, \tan(d) \approx 1\text{m}$), $3\mu\text{m}$, $dC_i \gg 1.2\text{pF}$
 $d\text{FWHM}_{\text{loss}} = 8.5/q \cdot \sqrt{(2kTC_i \tan(d))} \gg 180\text{eV}$



- + interconnect parasitic
- constraint on ASIC area and layout
- fluorescence from Pb (Sn/Pb/Ag)
- illumination from segmented side



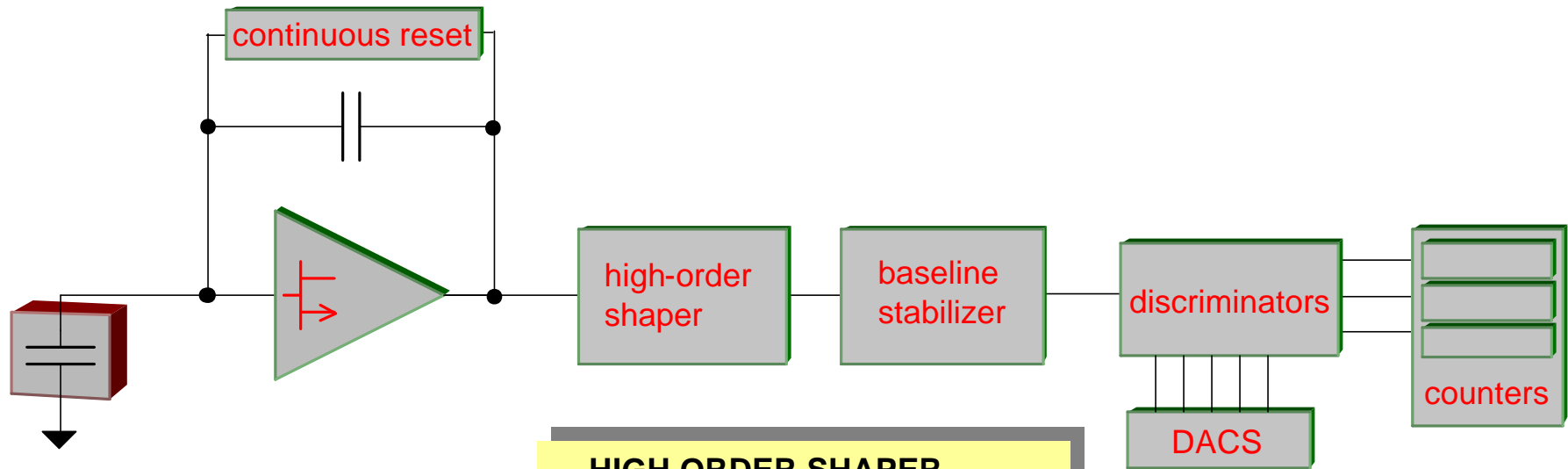
- + dielectric losses
- \pm interconnect parasitic
- bond length

Sensor – ASIC photo



one quadrant

ASIC channel overview



INPUT p-MOSFET

- optimized for operating region
- NIM A480, p.713

CONTINUOUS RESET

- feedback MOSFET
- self adaptive 1pA - 100pA
- low noise $3.5e^{-}$ rms @ 1 μ s
- highly linear 0.2% FS
- US patent 5,793,254
- NIM A421, p.322
- TNS 47, p.1458

≈ 3 mW

HIGH ORDER SHAPER

- amplifier with passive feedback
- 5th order complex semigaussian
- 2.6x better resolution vs 2nd order
- TNS 47, p.1857

BASELINE STABILIZER (BLH)

- low-frequency feedback, BGR
- slew-rate limited follower
- DC and high-rate stabilization
- dispersion 3mV rms
- stability 2mV rms @ $rt \times tp < 0.1$
- TNS 47, p.818

≈ 5 mW

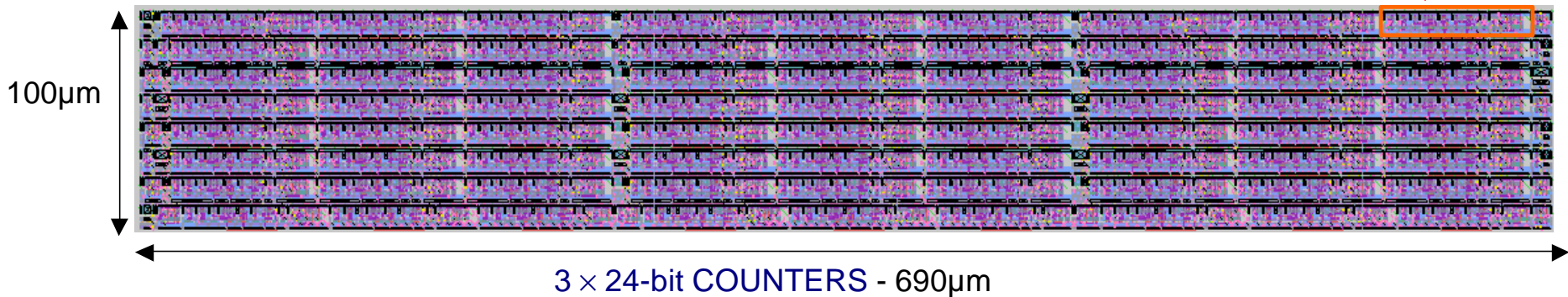
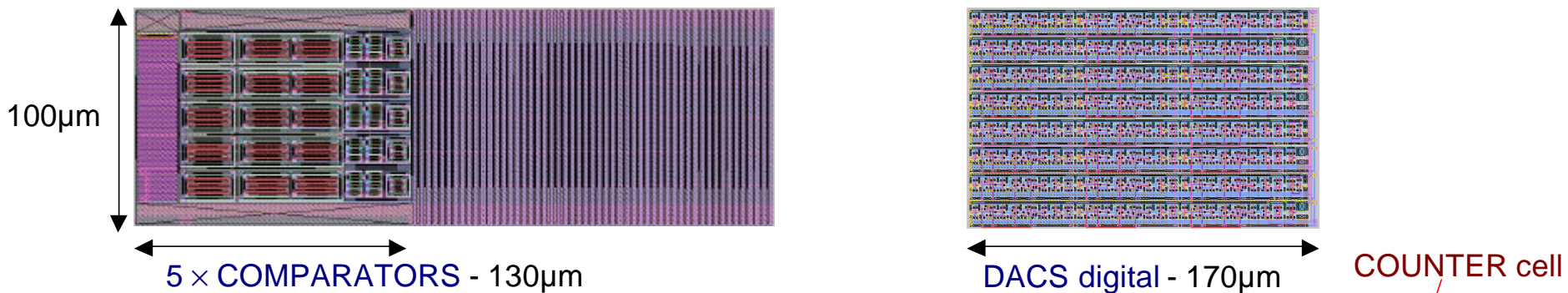
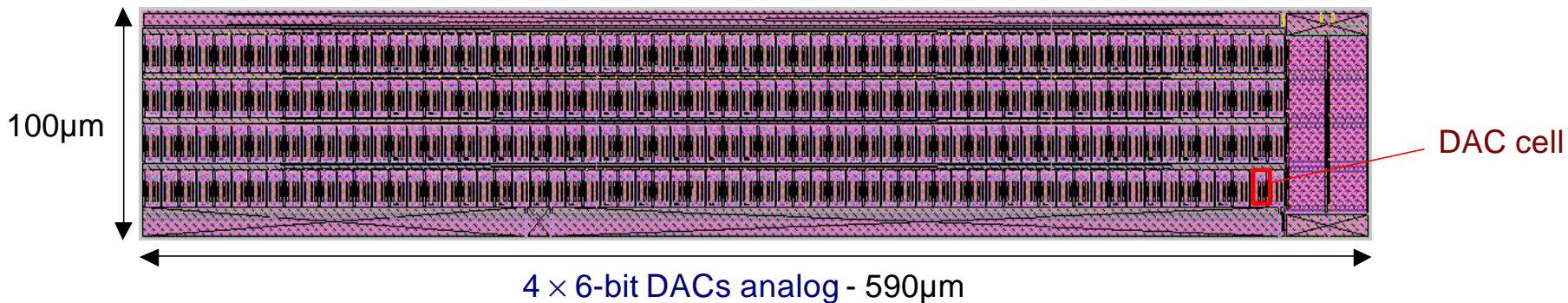
DISCRIMINATORS

- five comparators
- 1 threshold + 2 windows
- four 6-bit DACs (1.6mV step)
- dispersion (adj) $2.5e^{-}$ rms

COUNTERS

- three (one per discriminator)
- 24-bit each

ASIC layout cells



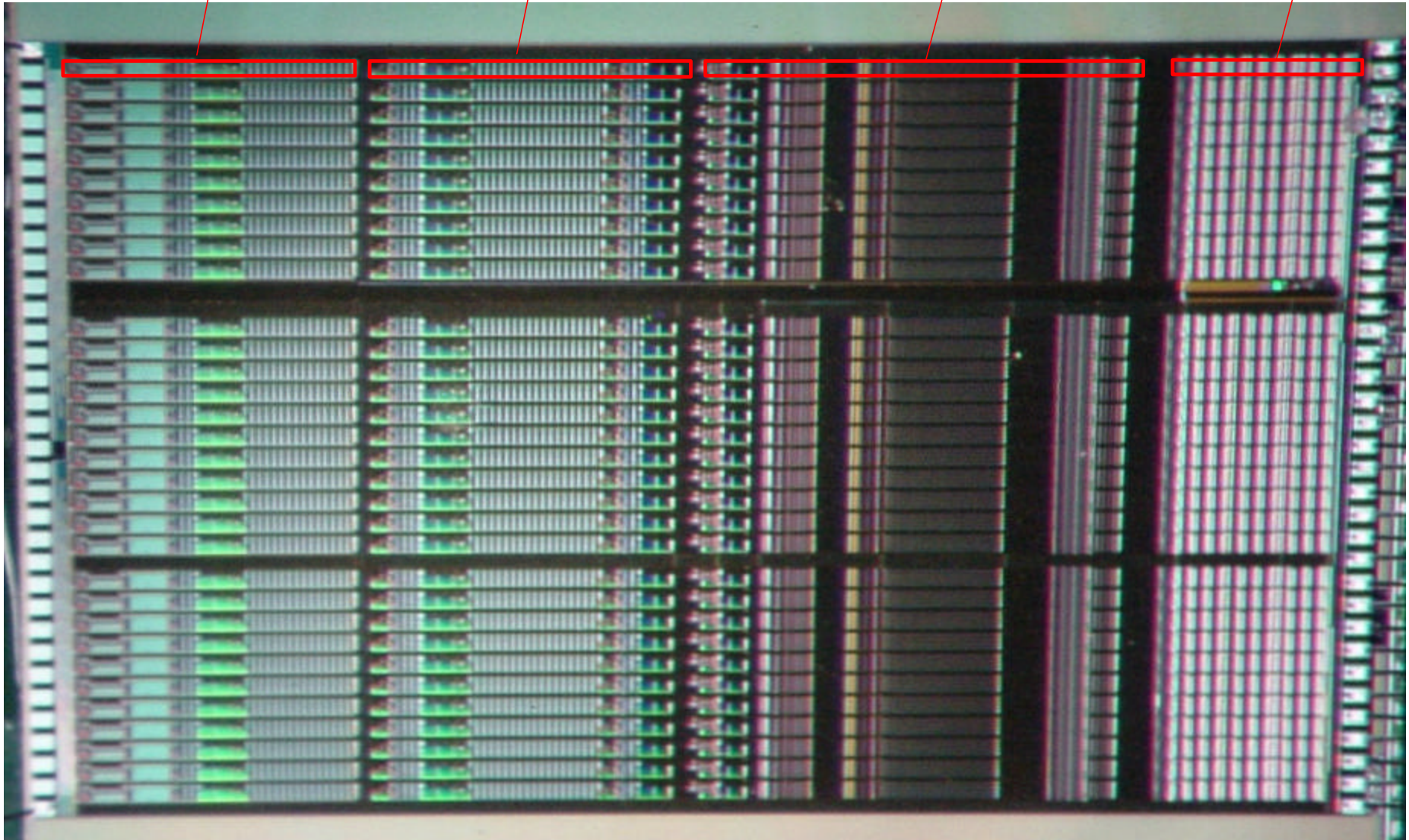
ASIC photo

charge preamplifier

shaper with BLH

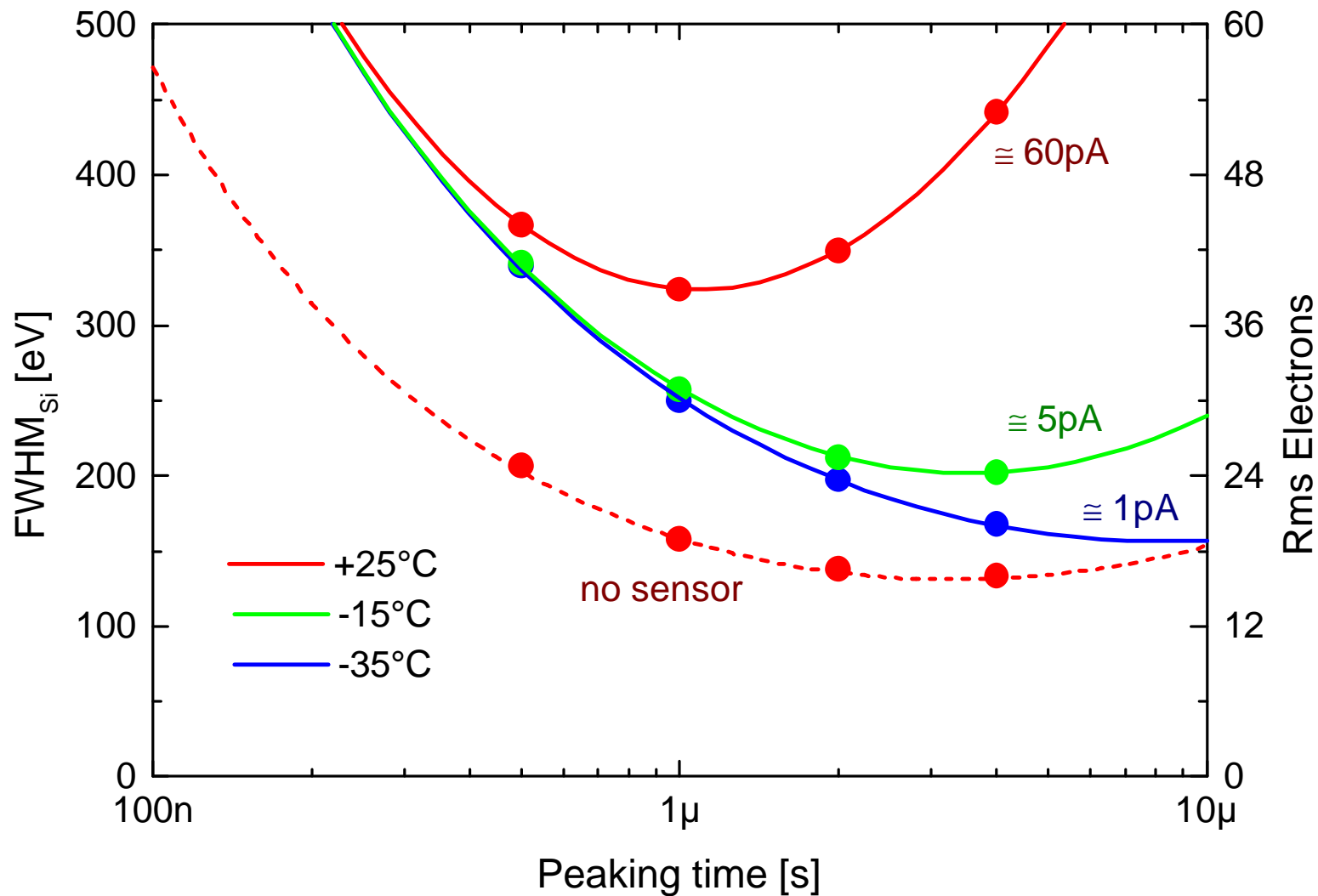
discriminators and DACs

counters



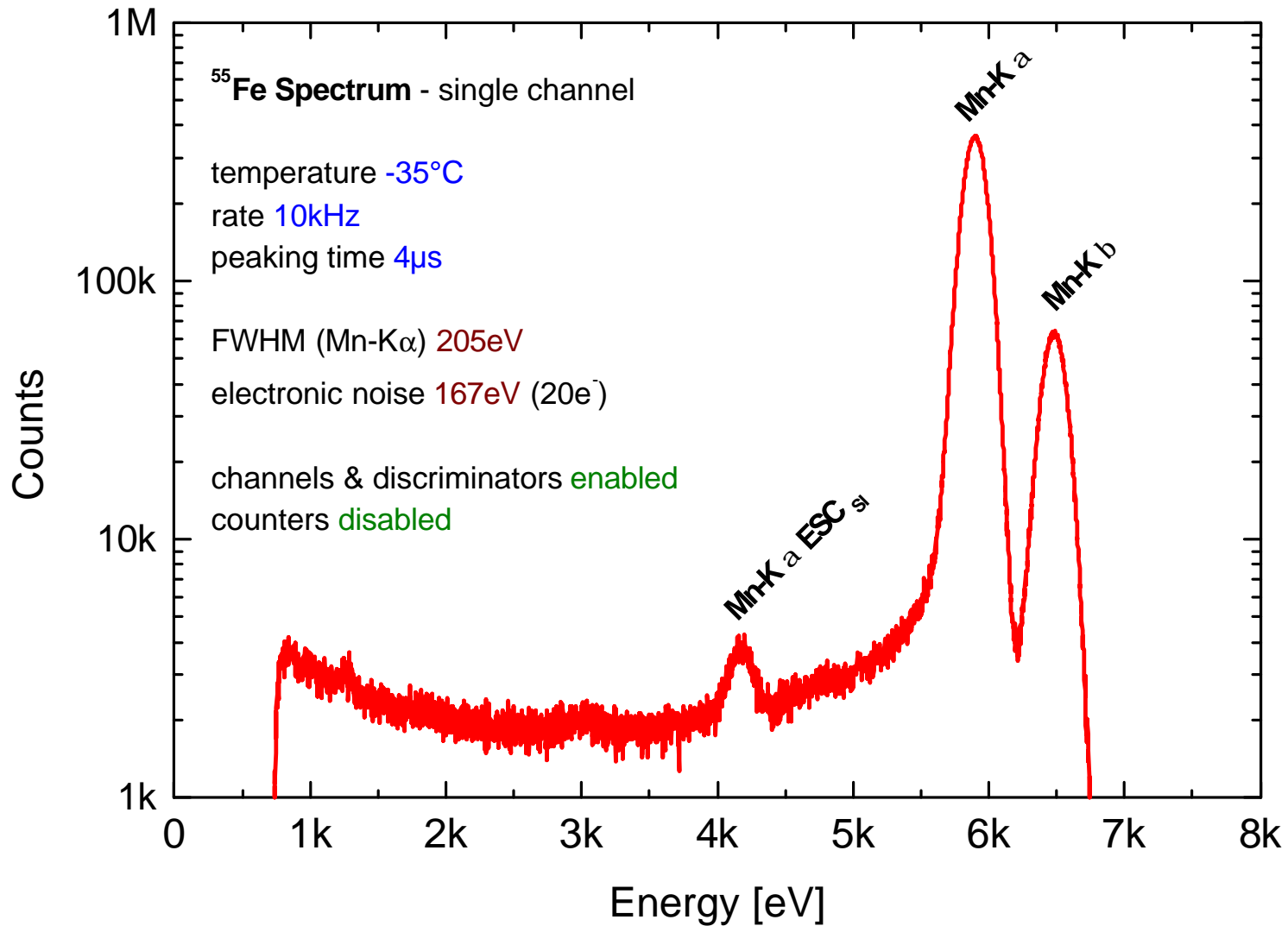
32 channels, 3.6 × 6.3 mm²

Measured resolution



50μm-gap, $C_p \approx 700\text{fF}$, $C_{i\text{-bond}} \approx 50\text{-}200\text{fF}$, $C_{i\text{-pad}} \approx 220\text{fF}$

^{55}Fe spectrum



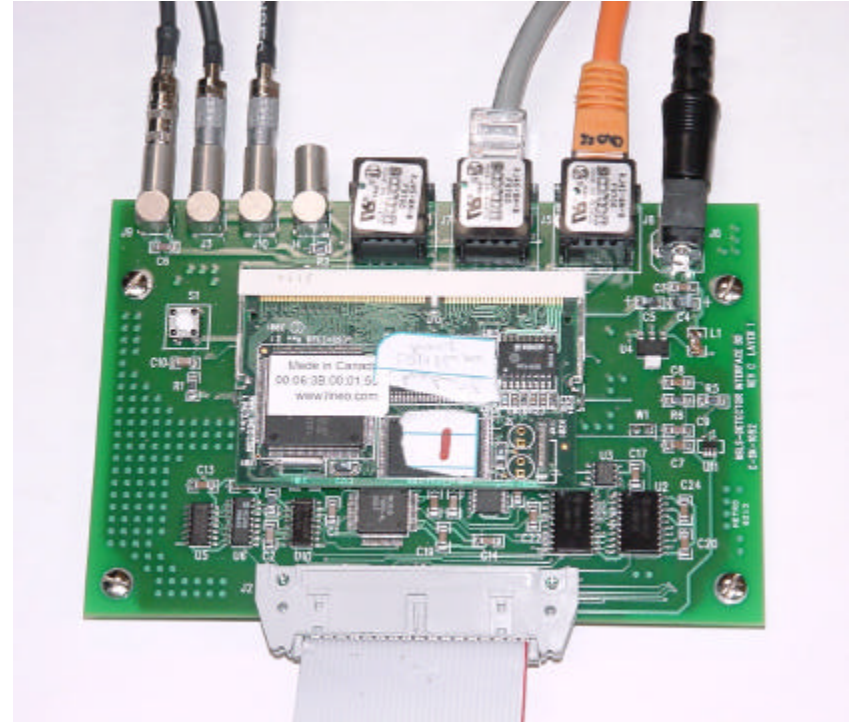
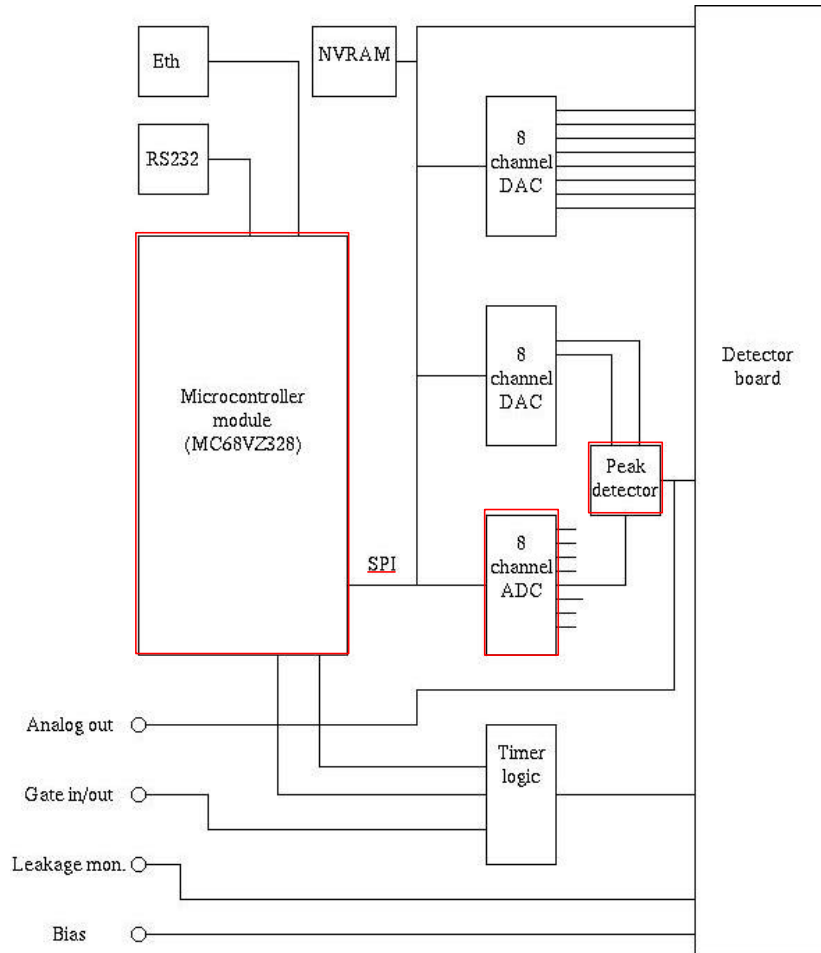
$50\mu\text{m-gap}$, $C_p \approx 700\text{fF}$, $C_{i\text{-bond}} \approx 50\text{-}200\text{fF}$, $C_{i\text{-pad}} \approx 220\text{fF}$

ASIC overview

Technology	CMOS 0.35 μ m 3.3V 2P4M
Size	$\approx 3.6 \times 6.3 \text{ mm}^2$
# MOSFETs	$\approx 180,000$
# Channels	32
power / channel	$\approx 8 \text{ mW}$
# Discriminators	three / channel (1 thr., 2 win.)
threshold adjustment	four 6-bit DACs (1.6mV step)
threshold dispersion (adj)	$\approx 2.5 \text{ electrons rms}$
# Counters	three / channel
bits per counter	24
Gain (settable)	750, 1500 mV/fC
Peaking time (settable)	0.5, 1, 2, 4 μ s
ENC @ 1μs	$\approx 14 + 12/\text{pF} \text{ electrons rms}$
ENC @ 4μs	$\approx 11 + 6/\text{pF} \text{ electrons rms}$

- self adaptive continuous **reset**
- high order **shaper**
- **band-gap** referenced output baseline
- output baseline **stabilizer** (BLH)
- **test capacitors**
- analog and pixel leakage monitors
- **plug & play** (fully self biasing)
- serial interface
 - counters readout
 - gain / peaking-time setting
 - monitors & test enable
 - channel masking
 - DACs setting
- token or chip-select mode

Readout



Readout interface

The screenshot displays the Readout interface software with several windows open:

- ASIC Operation controls:**
 - Gain: 1.0V/uC (selected), 0.5 V/uC
 - Shaping time: 0.5 us (selected), 1.0 us, 2.0 us, 4.0 us
 - Pixel: 67
 - Thresh: 0
 - SCA 1: 0
 - SCA 2: 0
 - Buttons: Channel disable, Enable Cal. Input, Enable Leakage Output, Enable Analog Output, Enable All Cal., Disable All Cal., Global Reset
 - Display F.S.: 1000
 - Count: [input field]
- Set levels:**
 - Thresh: 1024 / 1024
 - SCA 1 hi: 4095 / 4095
 - SCA 1 lo: 2299 / 2299
 - SCA 2 hi: 4095 / 4095
 - SCA 2 lo: 1239 / 1239
- Trim DAC Settings:**

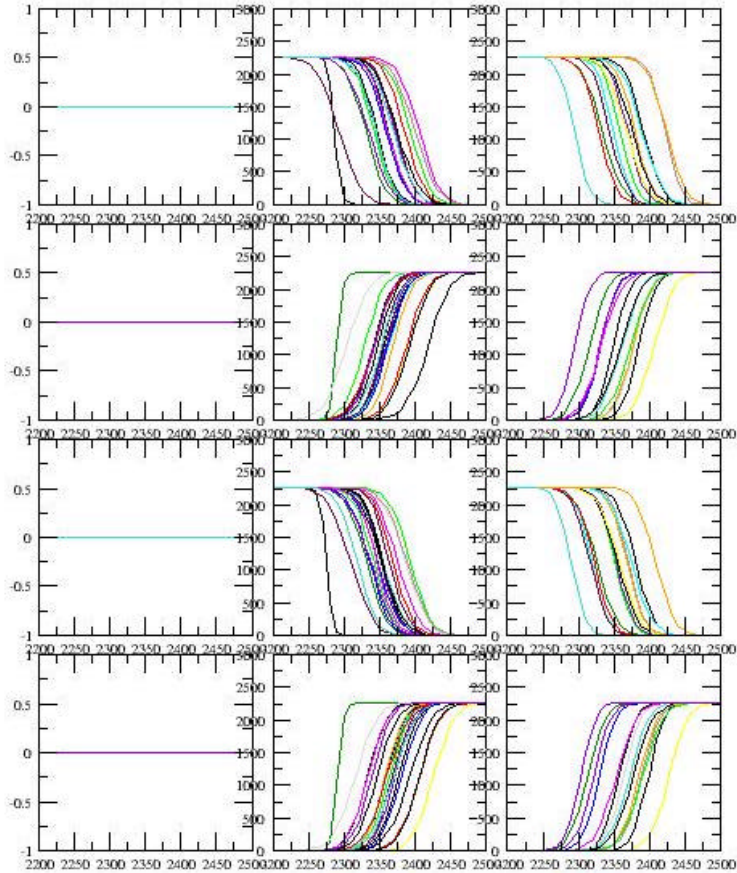
	A1hi	SCA2lo	SCA2hi
20	20	26	
63	63	57	
46	46	50	
48	48	56	
0	0	0	
0	0	0	
63	63	63	
61	61	41	
0	0	0	
63	63	63	
0	0	0	
0	0	0	
62	62	56	
60	60	58	
41	41	47	
57	57	61	
0	0	0	
48	48	54	
63	63	53	
0	0	0	
63	63	63	
21	21	48	47
22	0	0	0
23	63	63	63
24	0	0	0
25	48	55	48
26	0	0	0
27	52	63	56
28	0	0	0
29	0	0	0
30	34	33	23
31	38	44	48
- Console:**

```

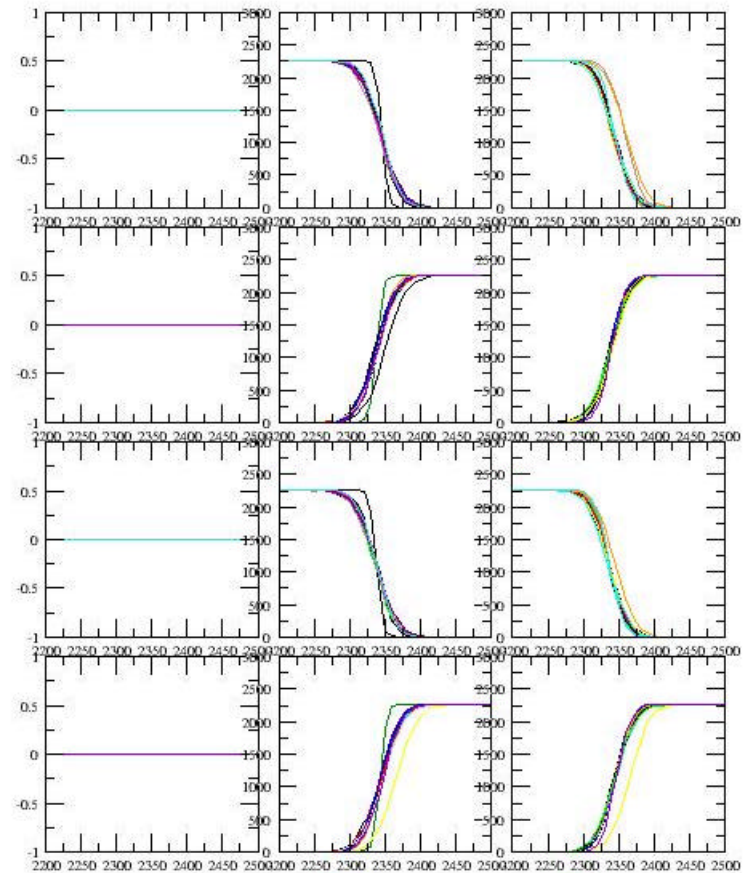
61:~/uClinux-dist-timer-mod/user/detect/python$ xvfb
command not found
61:~/uClinux-dist-timer-mod/user/detect/python$ ls /usr/doc/xvfb

```

Automatic threshold equalization

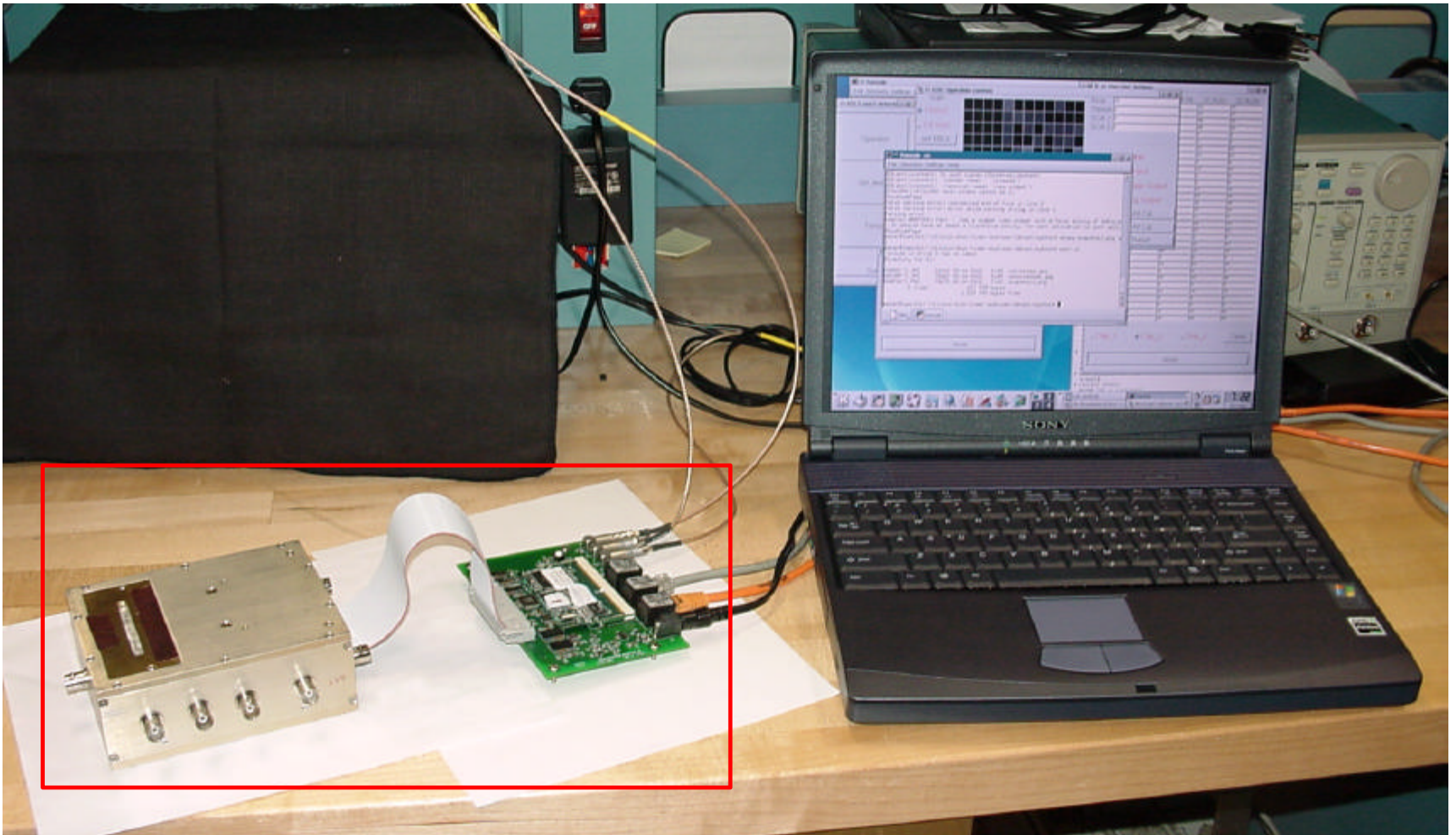


before correction $s \gg 170e$ rms



after correction $s \gg 2.5e$ rms

New EXAFS detector



» *400 channels, < 300 eV, > 10MHz*

Current EXAFS detector



head - *preamplifiers*

» 100 channels, > 350 eV, < 1 MHz



rack - *shapers ...*

Summary

New detector for EXAFS

- monolithic Si sensor, 400-mm² active area
- ≈ 400 1-mm² pixels
- 32-channel ASICs

First results (single quadrant)

- ENC $\approx 11 + 6/\text{pF}$ e⁻ rms @ 4 μ s
- FWHM < 300eV @ rate < 100 kHz/pixel
- threshold dispersion < 2.5 e⁻ rms

Future work

- one ASIC iteration
- pixel gap selection (10, 30, 50 μ m)
- Peltier cooler assembly / test
- four quadrant (12 ASICs) assembly / test
- on-field test at NSLS (BNL)